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126 nm VUV emission from an Ar*₂ excimer lamp excited by a dielectric barrier discharge

A coaxial Ar excimer lamp excited by a dielectric barrier discharge has been developed and characterized. The effect of discharge gas pressure on the intensity of the Ar 126 nm VUV emission has been investigated. Intensity of the VUV Ar*₂ excimer emission increases with pressure according to a second order polynomial.

Primary author: Mr BARICHOLO, Peter (National University of Science and Technology, Stellenbosch University)

Co-authors: Prof. VON BERGMANN, Hubertus M. (Laser Research Institute, University of Stellenbosch); Mr STEHMANN, Timo (laser Research institute, University of Stellenbosch)

Presenter: Mr BARICHOLO, Peter (National University of Science and Technology, Stellenbosch University)

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